

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: **KOZAWA, Miwa, et al.**

Serial Number: **Not Yet Assigned**

Filed: **September 26, 2003**

For. **RESIST PATTERN THICKENING MATERIAL, PROCESS FOR FORMING RESIST PATTERN, AND PROCESS FOR MANUFACTURING SEMICONDUCTOR DEVICE**

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

September 26, 2003

Sir:

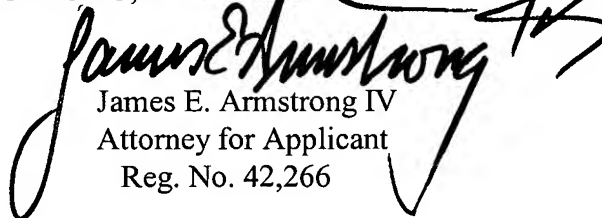
In compliance with 37 CFR 1.56, Applicants call to the attention of the Patent and Trademark Office the references listed on the attached PTO-1449.

A copy of each of the references are enclosed herewith.

In the event there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 01-2340.

Respectfully submitted,

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PATENT TRADEMARK OFFICE

Enclosures: PTO-1449; JP References w/ English Translations (2)

INFORMATION DISCLOSURE STATEMENT PTO-1449	Atty. Docket No. 031181	Serial No. New Application.
	Applicant(s): KOZAWA, Miwa, et al.	
	Filing Date: September 26, 2003	Group Art Unit: To Be Assigned

U.S. PATENT DOCUMENTS

Examiner Initial	Document No.	Name	Date	Class	Subclass	Filing Date (If appropriate)
_____	AA					
_____	AB					
_____	AC					
_____	AD					

FOREIGN PATENT DOCUMENTS

Document No.	Date	Country	Translation (Yes or No)
_____ AE 2002-6491	01/09/02	Japan	Yes
_____ AF 2002-49161	02/15/02	Japan	Yes
_____ AG			
_____ AH			
_____ AI			

OTHER DOCUMENTS

_____ AJ	
_____ AK	
Examiner	Date Considered